

26. The apparatus of claim 21 wherein the target and the substrate supporting surface are separated by a distance of at least about 50 mm.

27. A method for depositing a magnetic film within a sputtering chamber containing a target and a substrate, comprising:

sputtering the target onto a surface of the substrate at a pressure less than about 15 mTorr;

collimating sputtering of the target with a grounded collimator disposed between the target and the substrate; and

generating a magnetic field that is substantially parallel to the surface of the substrate during sputtering using an annular magnet array concentrically disposed around a perimeter of the surface of the substrate within the sputtering chamber.

28. The method of claim 27, wherein the sputtering occurs at a chamber pressure less than about 5 mTorr.

29. The method of claim 27, wherein the target and the surface of the substrate are maintained at a distance of at least about 50 mm during sputtering.

30. The method of claim 29, wherein the target comprises a Ni/Fe alloy.

31. The method of claim 27, wherein the grounded collimator removes charges from target particles and reduces interference with the parallel magnetic field.--

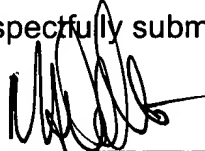
REMARKS

Applicants request entry and consideration of the above noted amendments prior to examination. Applicants have cancelled claims 1 – 3, 5 – 6, 15 – 16, and 18 – 20 from consideration and added new claims 21 – 31. Although Applicants believe that no fee is due in conjunction with this amendment, the Office is hereby authorized to charge

deposit account number 20-0782/2406.X1/CPES/DT/DV for any additional claim fees required in conjunction with this response.

Further, Applicants submit that the references cited by the Examiner in the previous actions, neither alone nor in combination, teach, show, or suggest the apparatus and method the invention as claimed herein. Applicants submit that the claims are in condition for allowance and respectfully request that the claims be allowed.

Respectfully submitted,



N. Alexander Nolte
Registration No. 45,689
MOSER, PATTERSON & SHERIDAN, L.L.P.
3040 Post Oak Blvd., Suite 1500
Houston, TX 77056
Telephone: (713) 623-4844
Facsimile: (713) 623-4846
Attorney for Applicant(s)